

STATE OF THE ART CONSTANT FLOW DEVICE

ABSTRACT

A method and apparatus assures constant fluid flow into a semiconductor processing tank. A flow meter is set to a flow rate, fluid from a point-of-use is routed through the flow meter into a processing tank, filling the tank to an overflow point. An overflow basin is provided from where the fluid is drained into a fluid reclaim vessel. Overflow is detected by a sensor, which activates an overflow relieve valve. The overflow relieve valve drains fluid, counteracting the overflow. Interaction between the overflow detector and the overflow relieve valve assures a constant rate of supply of fluid.

Fig. 1